



Singlet delta oxygen production by plasmas

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MOTIVATION



Aim: SDO production at atmospheric pressure for biomedical applications

Why Singlet Delta Oxygen $O_2(a^1\Delta_g)$?

SDO is well known to:

- Play a major role in several biological systems and processes
- > generate **oxidative damage** to a variety of biological components

[N.I. Krinsky, Singlet Oxygen, Academic Press, New York, 1979][L. Packer and H. Sies, Methods in Enzymology, Singlet Oxygen, UV A and Ozone, Academic Press, New York, 2000]

However, SDO is rather **difficult** to produce and to detect!

development of a plasma source for the controlled production of high fluxes of SDO at atmospheric pressure

including accurate quantification of SDO fluxes reaching biological targets





 \succ O₂(a¹ Δ_g):

 ✓ a very stable excited (0.98 eV) molecular state → easy to transport (long radiative lifetime ~74 min (in gas phase) and low quenching probability)

[A.A. Frimer, Singlet Oxygen, CRC Press, Boca Raton, 1985]

 \checkmark detection is rather challenging (A=2.2 10⁻⁴ s⁻¹) [S.M. Newnan et al., J. Chem. Phys. 110 (1999) 10749]

 ✓ efficient production by electric discharge is difficult → low E/N required (E/N_{opt} = 10 Td vs E/N_{ss} = 100 Td (in pure O₂))



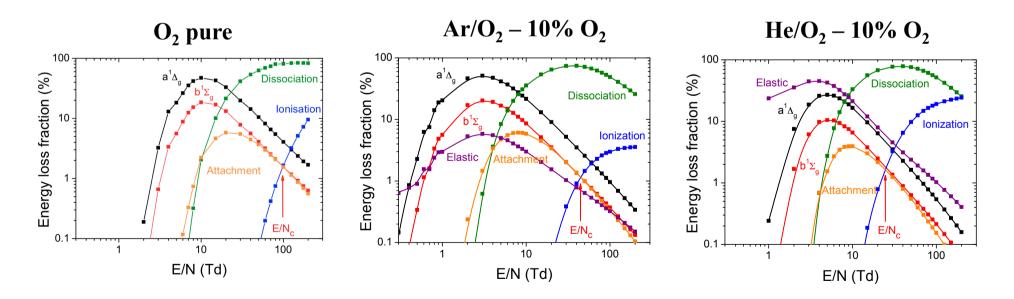


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FTOUL [P. Segur and M.C. Bordage in *Proceedings XIX ICPIG* 1989 Belgrade]

 $^{1 \}text{ Td} = 10^{-17} \text{ V.cm}^2$





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✓ high yield requires high specific deposited energy (~ $4-5 \text{ eV/O}_2$)

[M.J. Kushner, J. Phys. D: Appl. Phys. 38 (2005) 1633]

Potential applications:

Lasers: pumping of the oxygen-iodine laser [A.P. Napartovich, J. Phys. D: Appl. Phys. 34 (2001) 1827]

Biological applications





How do we generate SDO at amospheric pressure by electric discharges?

electric discharge operating at low reduced electric field

Efficient SDO production requires to separate:

- plasma production: high E/N
- **SDO excitation**: low E/N

stable electric discharge at high pressure and high power loading

Solutions to answer these two big issues:

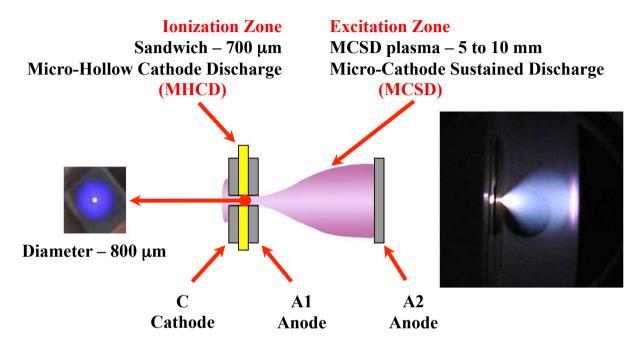
> non-self-sustained discharges [A.E. Hill in Proceedings LASERS 2000]

DC microdischarges: MHCD+MCSD [G. Bauville et al., Appl. Phys. Lett. 90 (2007) 031501]



MICRODISCHARGES





[R.H. Stark and K.H. Schoenbach, J. Appl. Phys. 85 (1999) 2075]

MCSD is similar to a **positive column**:

- ✓ low E/N and Tgas
- ✓ stable at high pressure and high power loading

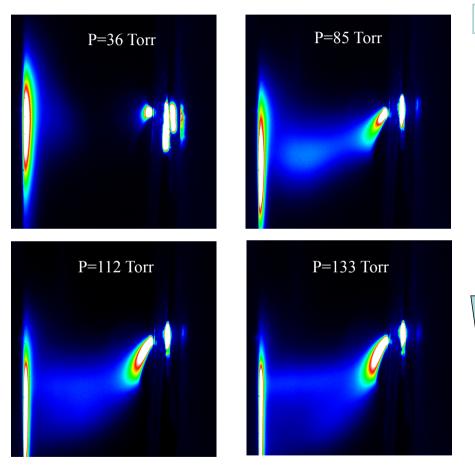
> MCSD have been proven efficient for $O_2(a^1\Delta_g)$ generation:

2007 (G. Bauville et al, Appl. Phys Lett 90, 031501)
2008 (J. S. Sousa et al, Appl. Phys Lett 93, 011502)
2010 (J. S. Sousa et al, Appl. Phys Lett 97, 141502)

10¹⁵ cm⁻³ in Ar/O₂ @ 100 mbar 10¹⁶ cm⁻³ in He/O₂/NO @ 1000 mbar 10¹⁷ cm⁻³ in MCSD arrays

PLASMA DEVELOPMENT in Ar/O₂ MIXTURES

O₂=5 torr, I=0.5 mA, Q(Ar)=430 sccm

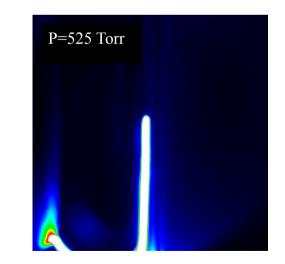


[J. S. Sousa et al, IEEE Trans. Plasma Sci. 39 (2011) 2680]

Gas Flow

In Ar/O_2 mixtures, MCSDs are blown by the gas flow but remain diffuse with a large radial expansion

Blowing occurs for Q>100 sccm



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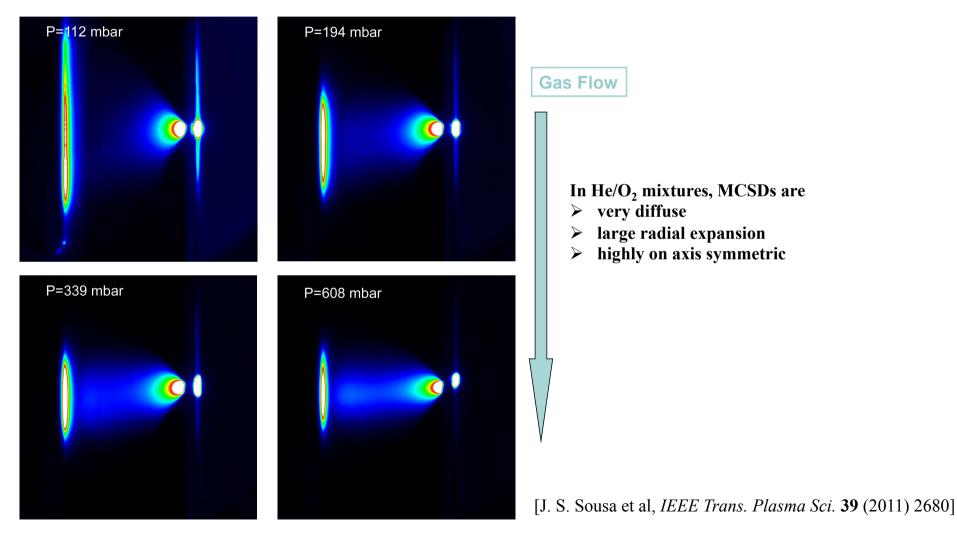
PARIS

CMIS

dramatic at higher pressures



O₂=7 mbar, I=0.5 mA, Q(He)=430 sccm





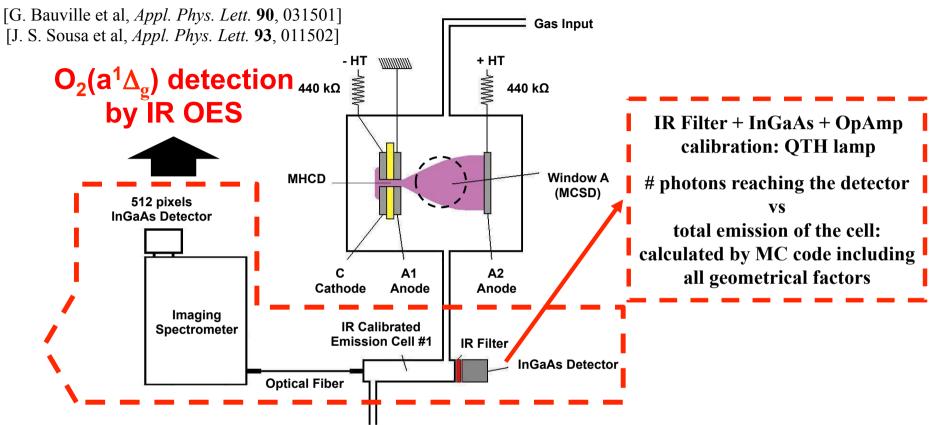
> MCSD characterisation by different optical diagnostic techniques:

 \Box O₂(b¹ Σ^+ _g) : OES @ 760 nm Gas input ✓ Tgas : 300 – 500 K + HT WWW 440 kΩ 440 kΩ **O**₃ : **O**AS @ 254 nm $\checkmark 10^{13} - 10^{16} \text{ cm}^{-3}$ Window A **n**_e: Stark broadening (in collaboration with Nader Sadeghi (LSP)) MHCD (MCSD) \checkmark 10¹³ cm⁻³ in pure Rg \checkmark non measurable in Rg/O₂ A1 A2 C **O-atoms : TALIF** (in collaboration with Lionel Magne (LPGP)) Cathode Anode Anode \checkmark confined to the discharge chamber Gas output $\Box O_2(a^1\Delta_g) : OES @ 1.27 \ \mu m$ ✓ dominated by Rg emission **BUT** long lifetime \longrightarrow afterglow measurements



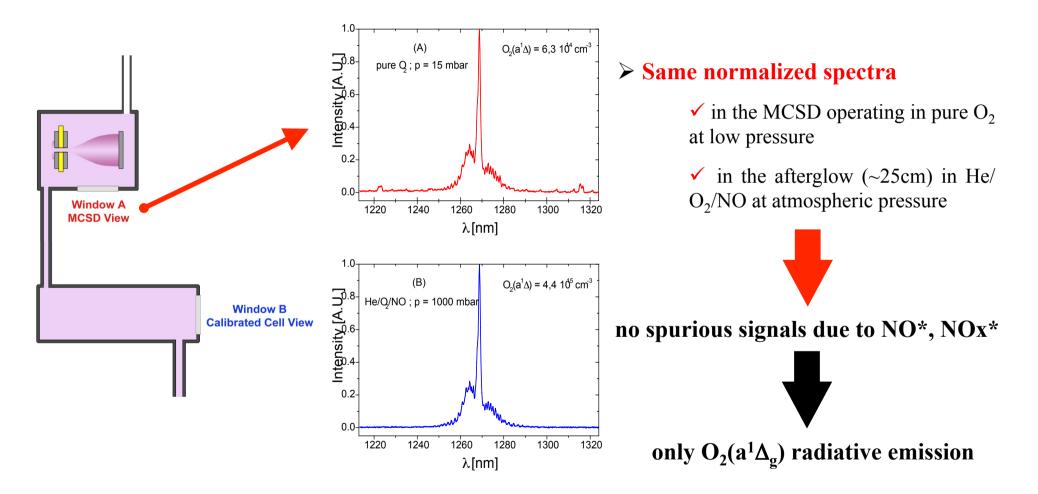
AFTERGLOW







> Measurement of the radiative emission of $O_2(a^1\Delta_g)$ at 1.27 μm

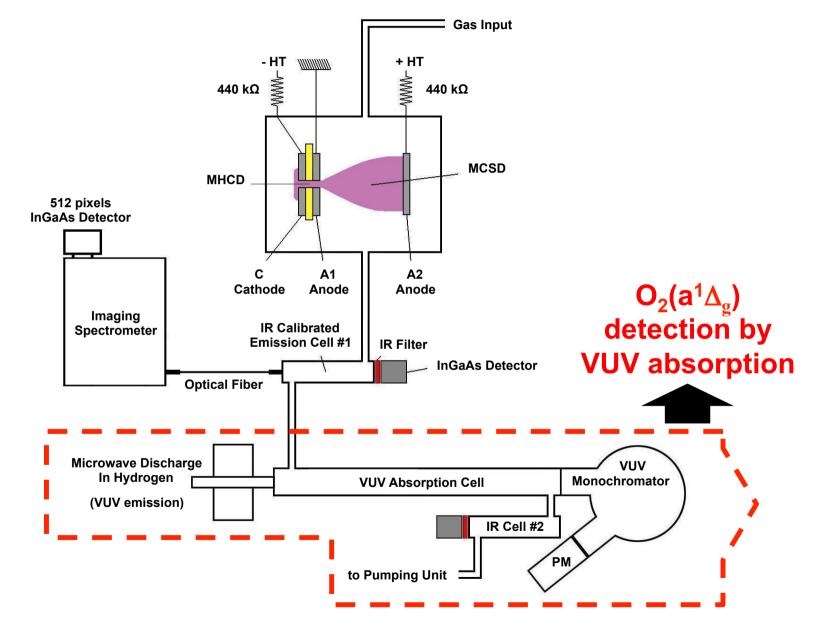


but what about the induced collision emission: (A=2.2 10⁻⁴ s⁻¹ / A=10² s⁻¹ in solvents)



AFTERGLOW







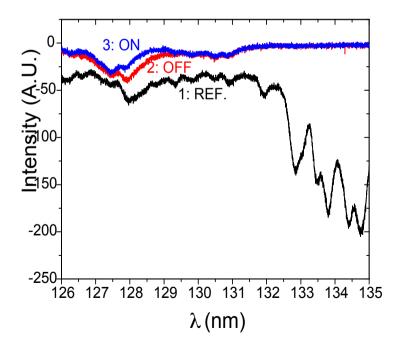


> Measurement of the $O_2(a^1\Delta_g)$ number density

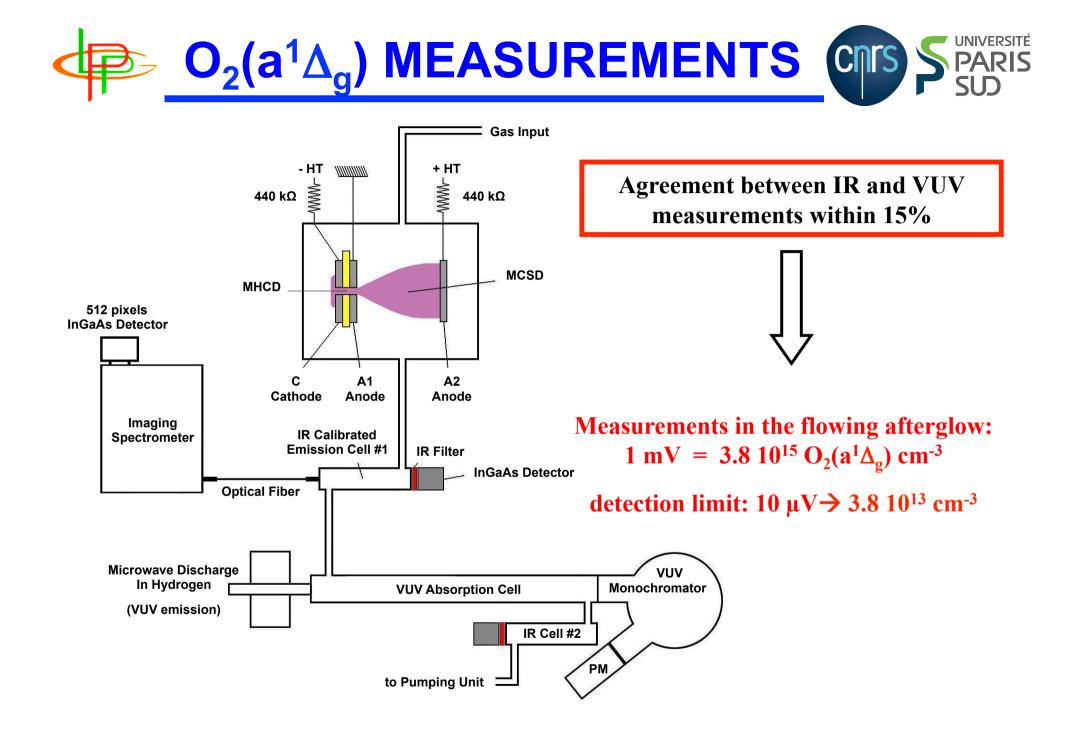
✓ VUV diagnostic to exclude any possibility of induced-emission collision

• $O_2(a^1\Delta_g)$ largely contribute to the light absorption between 125 and 130 nm

At 128.5 nm $\sigma_a[O_2(a^1\Delta_g)] = 1.67 \ 10^{-17} \ cm^2$ 40 times greater than $\sigma_X[O_2(X^3\Sigma_g)] = 4 \ 10^{-19} \ cm^2$ [S. Ogawa, Can. J. Phys. 59 (1975) 1845]

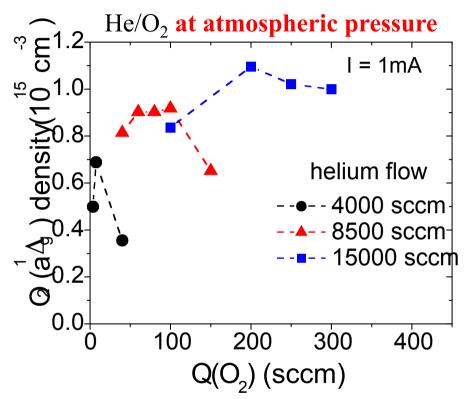


 $O_2(a^1\Delta_g)$ number density deduced by the relation: $ln(I_0/I) = [O_2(a^1\Delta_g)] \cdot \sigma_a \cdot L + [O_2(X^3\Sigma_g)] \cdot \sigma_X \cdot L$



INFLUENCE OF FLOW

 $O_2(a^1\Delta_{\alpha})$ **PRODUCTION**





[J. S. Sousa et al, J. Phys. D: Appl. Phys. 46 (2013) 464005]

In He/O₂ mixtures **at atmospheric pressure**:

> $O_2(a^1\Delta_g)$ quenching by O-atoms and O_3 for long residence time

➤ main destruction channels: $O_2(a^1\Delta_g) + O + He \rightarrow O_2(X^3\Sigma_g) + O + He$ $O_2(a^1\Delta_g) + O_3 \rightarrow O + O_2(X^3\Sigma_g) + O_2(X^3\Sigma_g)$

 \triangleright O₂(a¹ Δ_g) density ~10¹⁵ cm⁻³, whenever:

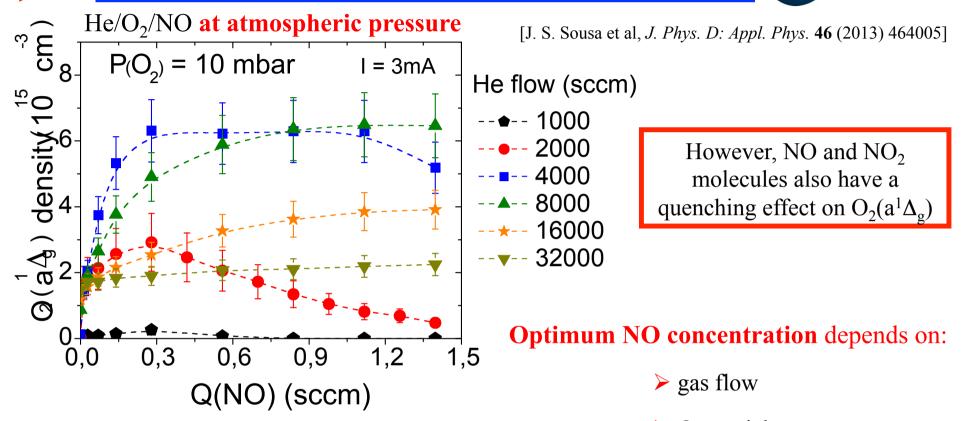
- helium flow > 10000 sccm (very high gas flow)
- O_2 concentration ~2%

In order to obtain greater $O_2(a^1\Delta_g)$ densities:

➤ addition of O-atom and O₃ scavengers: NO



INFLUENCE OF NO



Influence of adding NO molecules at low concentration:

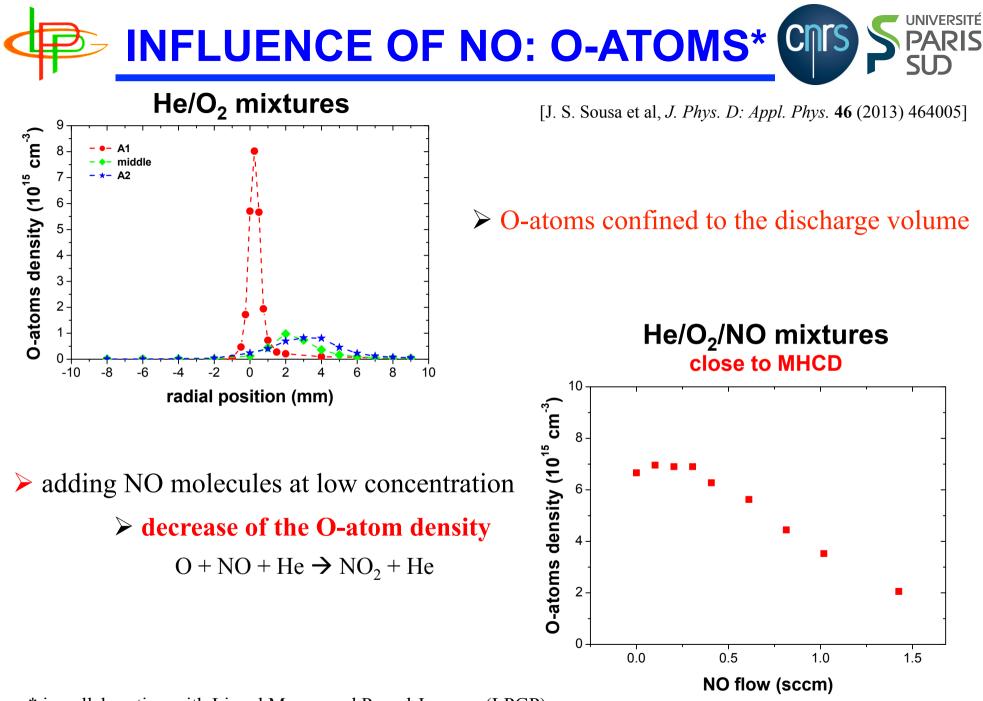
decrease of the O-atom density

 $O + NO + He \rightarrow NO_2 + He$

- > large increase of $O_2(a^1\Delta_g)$ density (x6)
- $> O_2(a^1\Delta_g)$ densities higher than 10¹⁵ cm⁻³

- > O₂ partial pressure
- energy deposited per O₂ molecule (P/Q)

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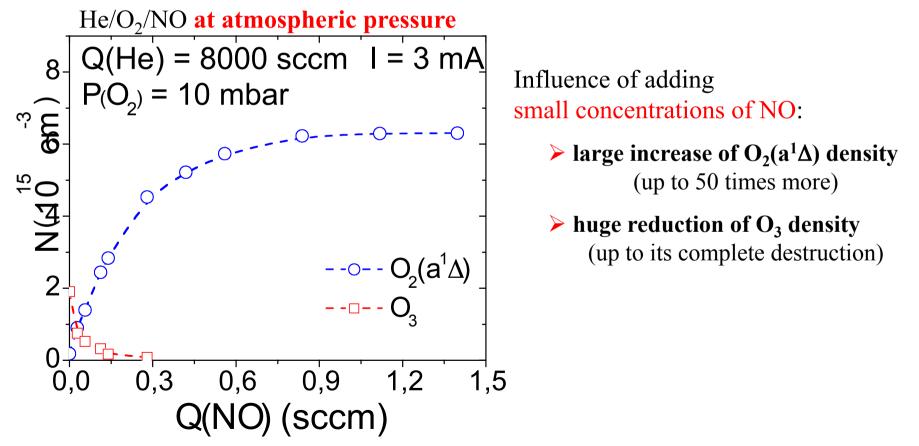
* in collaboration with Lionel Magne and Pascal Jeanney (LPGP)



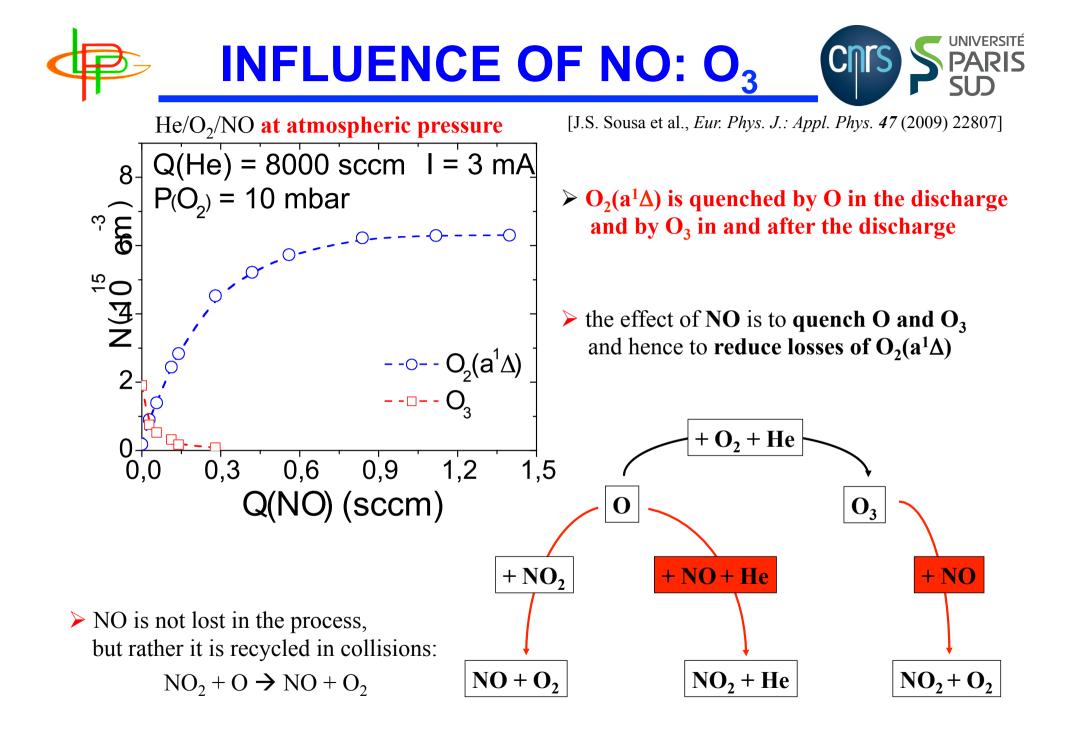


> Measurement of the O₃ number density by UV absorption

✓ O₃ largely contribute to the light absorption at 254 nm : σ [O₃] = 1.15 10⁻¹⁷ cm²

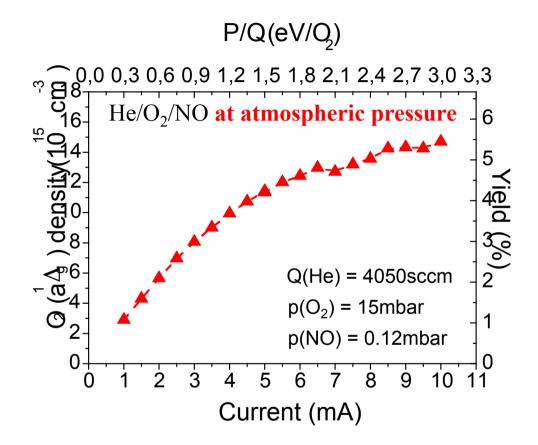


[J. S. Sousa et al, J. Phys. D: Appl. Phys. 46 (2013) 464005]

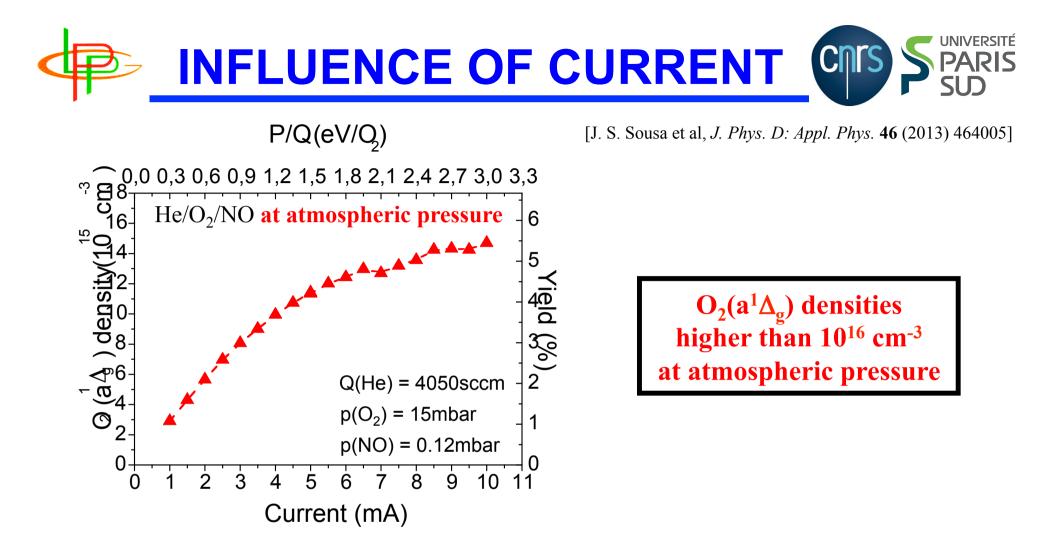




[J. S. Sousa et al, J. Phys. D: Appl. Phys. 46 (2013) 464005]



➢ O₂(a¹∆_g) density increase is nearly linear up to 3 mA ➢ O₂(a¹∆_g) density begins to saturate at higher currents



for producing $O_2(a^1\Delta_g)$ densities greater than 10^{16} cm⁻³, higher currents seem to be needed, but P/Q is near its optimum value

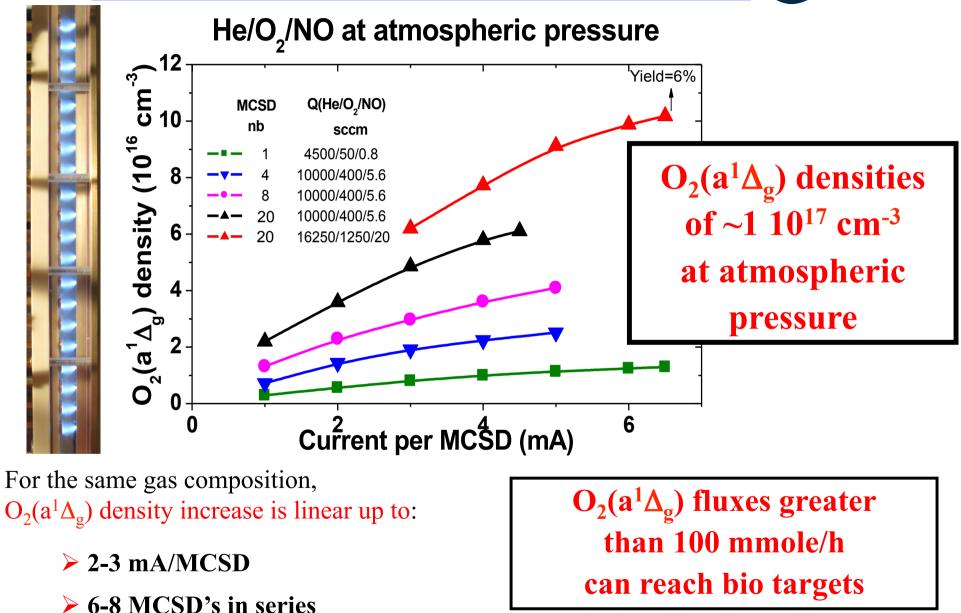


 $O_2(a^1\Delta_g)$ generation can be improved by using arrays of several MCDS's



MCSD's IN SERIES





[J.S. Sousa et al., Plasma Sources Sci. Technol. 22 (2013) 035012]



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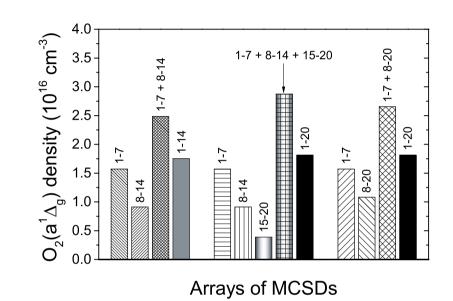


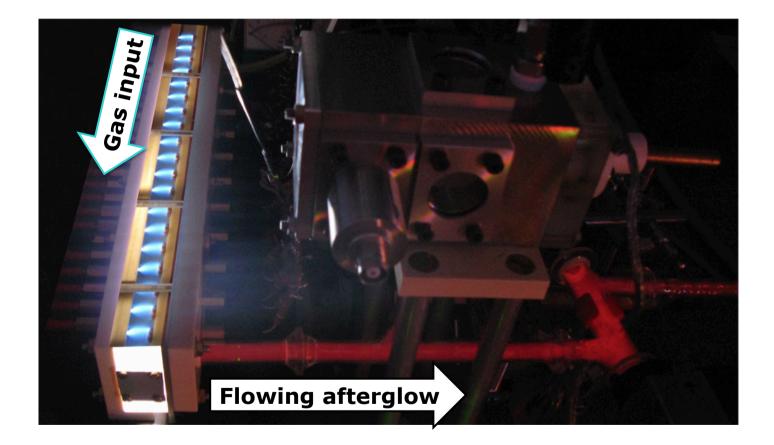
Figure 10. $O_2(a^1\Delta_g)$ density measured in the effluent, at 30 cm downstream of the last MCSD, while operating six different arrays of MCSDs (1–7, 8–14, 15–20, 8–20, 1–14, 1–20) at 3.5 mA per MCSD in He/O₂/NO mixtures, at a total gas flow of 4.6 slm and O₂ and NO partial pressures equal to 11 and 0.17 mbar, respectively. The theoretical sum of the O₂($a^1\Delta_g$) densities obtained with several arrays of MCSDs is also shown in columns 3, 8 and 12. Note that the number of active discharges increases with increasing distance to the detection cell, i.e. MCSD #1 and #20 are located at 30 and 53.75 cm upstream of the detection cell, respectively.







[J.S. Sousa et al., Plasma Sources Sci. Technol. 22 (2013) 035012]

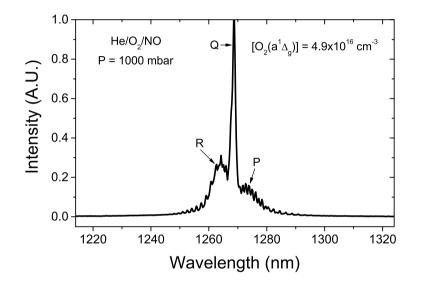


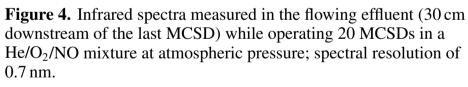






[J.S. Sousa et al., Plasma Sources Sci. Technol. 22 (2013) 035012]





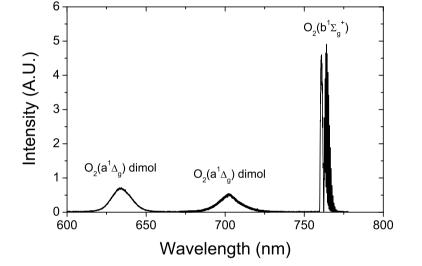


Figure 5. $O_2(a^1 \Delta_g)$ dimol emission around 634 and 703 nm and $O_2(b^1 \Sigma_g^+)$ emission around 762 nm in the flowing effluent (30 cm downstream of the last MCSD), while operating 20 MCSDs (3 mA per MCSD) in a He/O₂/NO mixture at atmospheric pressure (10 slm of He, 3.8% of O₂ and 358 ppm of NO); spectral resolution of 0.13 nm.







[J.S. Sousa et al., Plasma Sources Sci. Technol. 22 (2013) 035012]

O₂(
$$a^{1}\Delta_{g}$$
)(V = 0) + O₂($a^{1}\Delta_{g}$)(V = 0) → O₂($X^{3}\Sigma_{g}^{-}$)
× (V = 0) + O₂($X^{3}\Sigma_{g}^{-}$)(V = 0) + hυ (634 nm)

O₂($a^{1}\Delta_{g}$)(V = 0) + O₂($a^{1}\Delta_{g}$)(V = 0) → O₂($X^{3}\Sigma_{g}^{-}$) × (V = 1) + O₂($X^{3}\Sigma_{g}^{-}$)(V = 0) + hυ (703 nm).

O₂(
$$a^{1}\Delta_{g}$$
) + O₂($a^{1}\Delta_{g}$) → O₂($X^{3}\Sigma_{g}^{-}$) + O₂($b^{1}\Sigma_{g}^{+}$)
→ O₂($X^{3}\Sigma_{g}^{-}$) + O₂($X^{3}\Sigma_{g}^{-}$) + hv (762 nm).

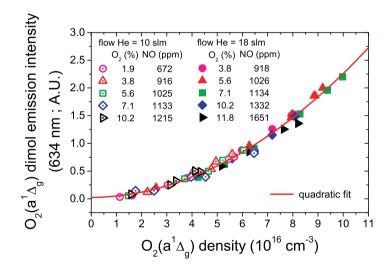


Figure 13. Evolution of the intensity of the $O_2(a^1 \Delta_g)$ dimol emission (in arbitrary units) versus the $O_2(a^1 \Delta_g)$ densities obtained in the effluent at 30 cm downstream of the last MCSD for several experimental conditions.

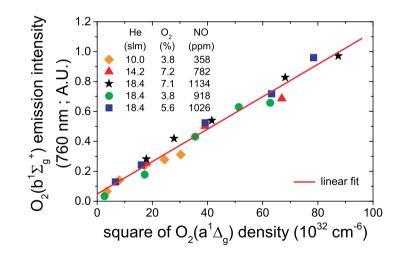


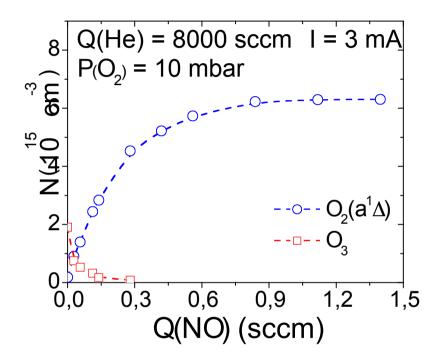
Figure 14. Evolution of the intensity of the $O_2(b \, {}^1\Sigma_g^+)$ emission (in arbitrary units) versus the square of the $O_2(a \, {}^1\Delta_g)$ densities obtained in the effluent at 30 cm downstream of the last MCSD for several experimental conditions.

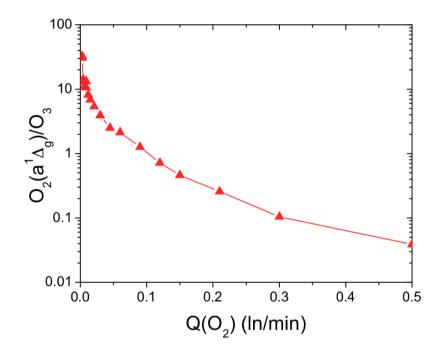


BIO APPLICATIONS

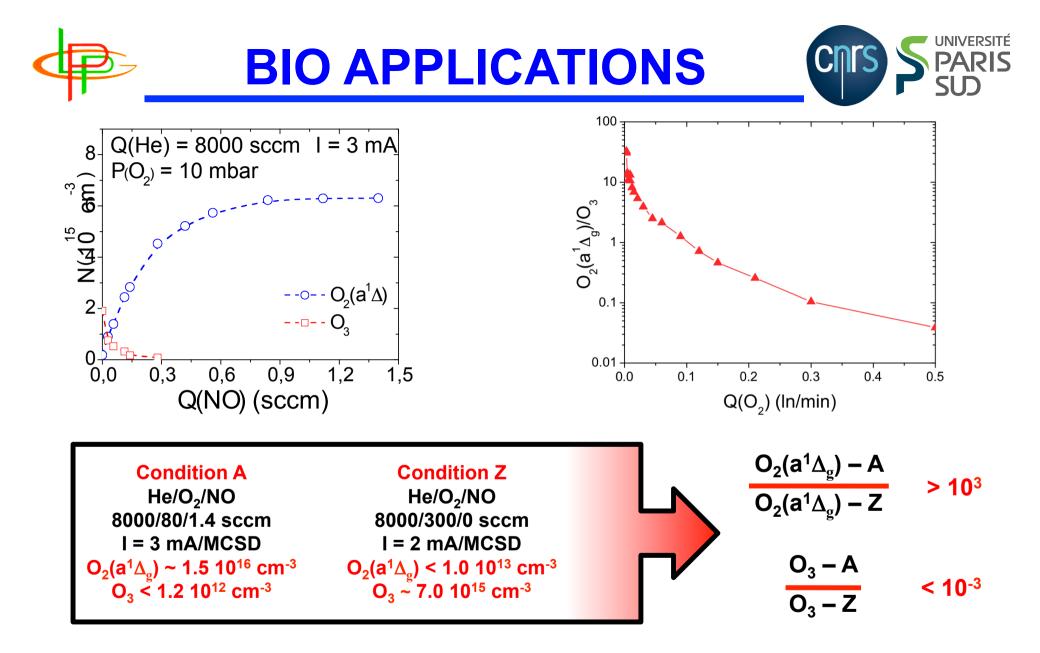


[J.S. Sousa et al., Plasma Sources Sci. Technol. 22 (2013) 035012]





> the density ratio of $O_2(a^1\Delta_g)$ to O_3 can be easily and finely tuned through the discharge current, and the O_2 and NO concentration → the maximum and minimum values of the density ratio of $O_2(a^1\Delta_g)$ to O_3 are obtained using the detection limits and are, thus, underestimated



MCSD's appear to be very suitable and useful tools

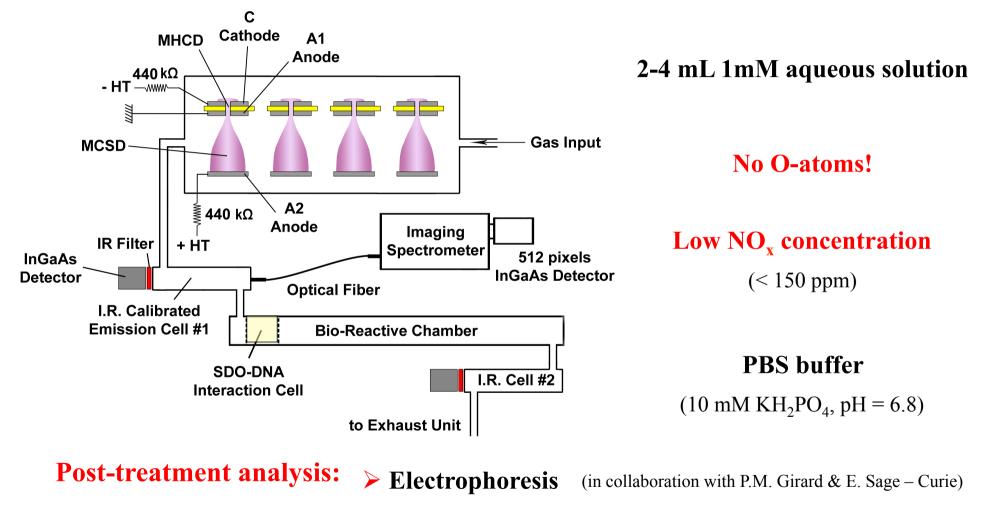
for examining the biological components targeted by these different ROS



DNA OXIDATION



> DNA (in solution) oxidation by $O_2(a^1\Delta_g)$ and O_3 at ~25cm downstream



HPLC-tandem MS (in collaboration with J.L. Ravanat – CEA)

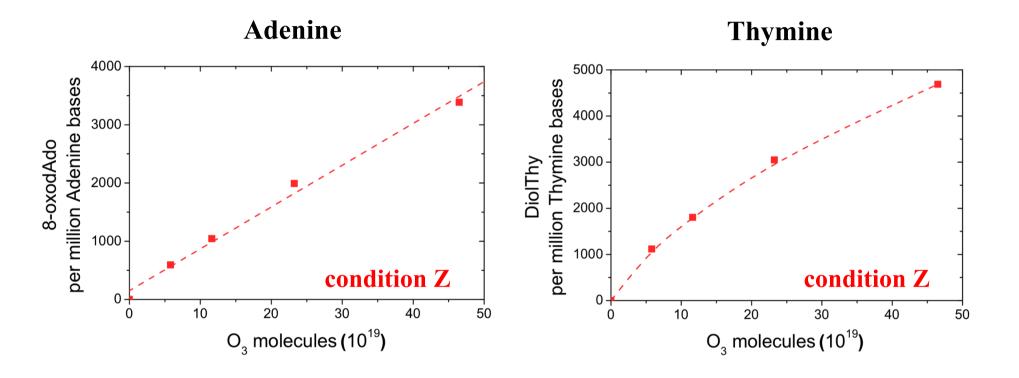


DNA OXIDATION



[J. S. Sousa et al, **DOI 10.1007/978-94-007-2852-3_9** (Ch9, pp107–119), Springer Science+Business Media B.V. (2012)]

DNA oxidation by O₃ was achieved!



• oxidized nucleosides production increases almost linearly with the O₃ flow

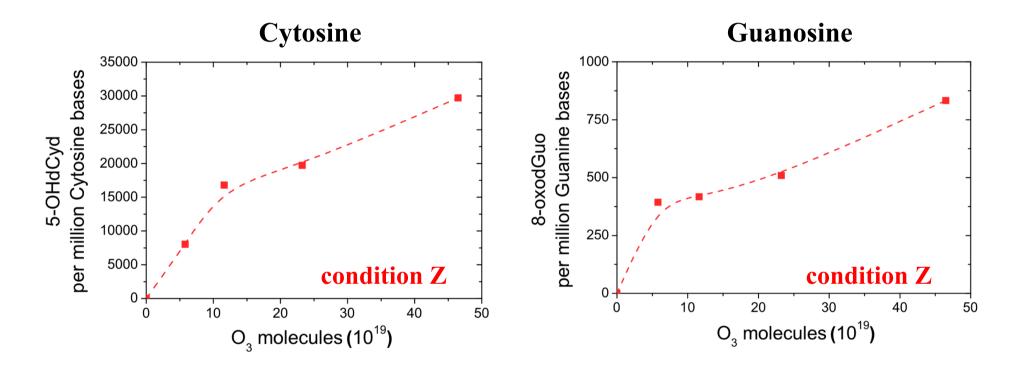






> Actually, O₃ overoxidized DNA!

[J. S. Sousa et al, **DOI 10.1007/978-94-007-2852-3_9** (Ch9, pp107–119), Springer Science+Business Media B.V. (2012)]



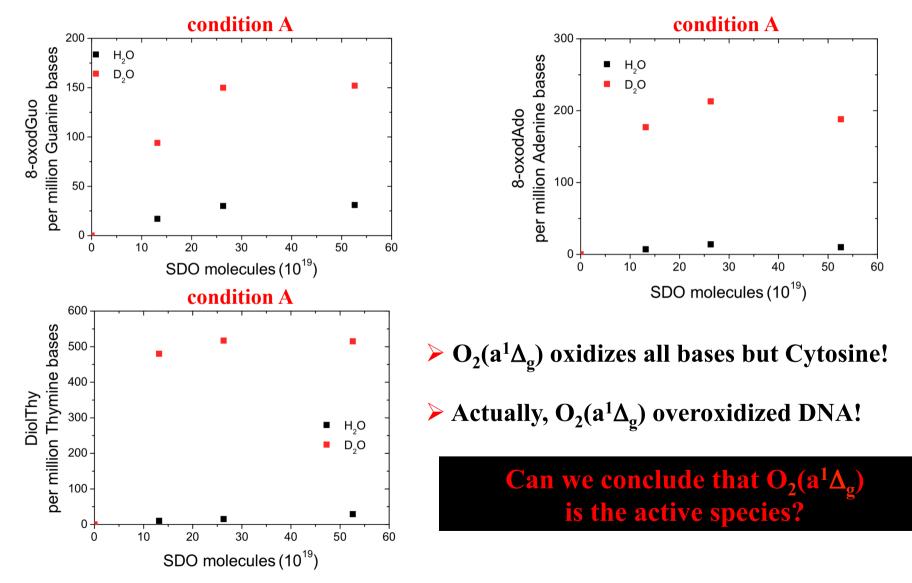
> 5-OHdCyd and 8-oxodGuo are easily oxidized [T. Douki et al., Radiat. Res. 153 (2000) 29]

O₃ is very effective on oxidizing Cytosine





> DNA oxidation by $O_2(a^1\Delta_g)$ was also achieved!





DNA OXIDATION



	Α	Z	O3 damage
	O ₂ (a ¹ ∆) ~ 1.5 10 ¹⁶ cm ⁻³	$O_2(a^1\Delta) < 1.0 \ 10^{13} \ \mathrm{cm}^{-3}$	/
	$0_3 < 8.0 \ 10^{12} \ \mathrm{cm}^{-3}$	O ₃ ~ 7.0 10 ¹⁵ cm ⁻³	$O_2(a^1\Delta)$ damage
8-oxoAdo	20	3385	~170
8-oxodGuo	30	833	~28
DiolThy	40	4689	~117
5-OHdCYd	14	29706	~2122

> 10 times more damages in condition A than those which could be induced by residual O_3

BUT

 \checkmark O₂(a¹ Δ_g) is physically de-excited in water

✓ possible role of NO_X → HNO_3 in solution (under investigation)

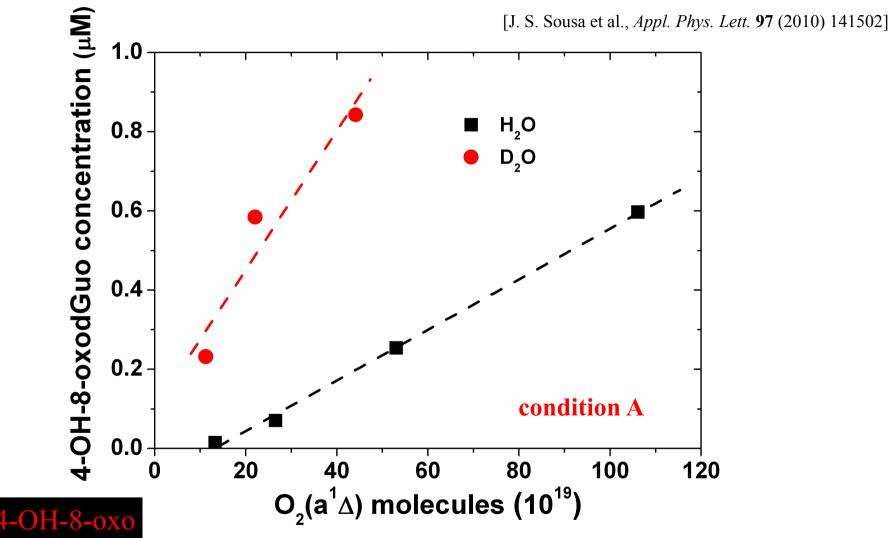
- **>** both O_3 and $O_2(a^1\Delta_g)$ seem to oxidize DNA
- **O**₃ seems to be more effective on oxidizing DNA

More experiments need to be done in order to clearly understand the reactivity of $O_2(a^1\Delta_g)$ and O_3 with DNA



dGuo OXIDATION





> results from dGuo oxidation by $O_2(a^1\Delta_g)$?

✓ 4-OH-8-oxo production increases linearly with $O_2(a^1\Delta_g)$ flow